



CP 2823

JPW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Antonio L. P. Rotondaro

Docket No: TI-31133

Serial No: 10/001,483

Conf. No: 1903

Examiner: Michelle Estrada

Art Unit: 2823

Filed: 11/01/2001


For: METHOD TO IMPROVE THE UNIFORMITY AND REDUCE THE SURFACE ROUGHNESS  
OF THE SILICON DIELECTRIC INTERFACE

**AMENDMENT UNDER 37 C.F.R. § 1.111**

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)**

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 11-23-04.

  
Ann Trent

Dear Sir:

Responsive to the Office Action mailed August 5, 2004, in connection with the above identified application, Applicant respectfully submits the following amendments and remarks.